

			GSD 200E (180kV)
			Serial No. 80275
			Late 1996
AREA	ITEMS	DETAIL	
SOURCE	Source head	ELS(Extended Life Source)	Enhanced Source w/ Tantalum
	High voltage bushing	extended life (part#1091180,110048950)	Shipped w/ standard
	Extraction Electrode	3 Axis extraction electrodes (SEN)	Yes
	Extraction	Pre and Post Extraction	90kV / 90kV
	Source analyzer	triple indexed mass analysis magnet & power supply	Yes
	RGA Resolver	Port	Yes
	RGA Chamber	Port	Yes
	HYT	Particle Detection Monitor	Yes
	MER		Yes
	PEF	Plasma Shower	Yes - E-Shwr IV (Fwd Bias)
	POST ACCEL ELECT	Manipulator	Yes
	Flag Faraday	Installed	Yes
END STATION	Wafer Size	8-inch Configured	Yes
	In-Air wafer handling	Automatic notch aligner (dual sensor)	Yes
		200mm Four cassette table	Yes - 280MM
		Dummy cassette 25 slot	Yes
		Vacuum cassette	Yes
		Loadbuffer #1, #2	Yes
		In-air robot	Yes
	In-Vac wafer handling	In-vac arm	Yes
		Holder	Yes
		Unclamp	Yes
		Elevator	Yes
	Gryo drive	Two Axis Variable Implant Angle	Yes - +/- 11 degrees in both axes
	Drive		Rotary Drive
Disk	200mm HUB Disk	Segmented SI Disk	
CONTROL SYSTEM	Cell controller	V6	Shipped w/ 133
	Dose Controller	Universal dose controller II (UDC2)	Real-time patented Dose Control
		SOLARIS & SPC	Shipped w/ SUN OS
		ULTRA	Shipped w/ Sparc 5 (Pri)

	SUN workstation	Remote Workstation	Shipped w/ SPARC 5 (Sec)
		SECS-I and SECS II protocols	Yes
		GEM interface and Ethernet port	Yes
	Disk chiller	Affinity Disk chiller	Yes w/ remote up to 50 ft
	COMPRESSOR	CTI 9600	Yes - 9600 and/or 8200
GAS BOX	Arsenic (SDS)	UNIT	n/a
	Phosphorus (SDS)	UNIT	n/a
	Boron (High pressure)	UNIT	STEC 4400 (CGA 330)
	XE	Installed	Yes
	Argon (High pressure)	UNIT	STEC 4400 (CGA 580)
PUMP	RP1	TYPE	EBARA 40 X 20
	RP2/3	TYPE	EBARA 40 X 20
	P1	Seiko Seiki A22003C	Seiko Seiki H2000C
	P2	CTI OB 8	Yes
	P3	CTI OB 10	Yes
VACUUM GAUGE	IG1	Hot cathode ion gauge	307
	IG2	Stabil	307
	IG3	Stabil	307
	IG4	Hot & Cold cathode ion gauge	307